

Docket Number: 081469-0306369
Client Reference: P-1790.000-US

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of

OTTENS et al.

Group Art Unit:

Application No.: TO BE ASSIGNED

Examiner:

Filed: December 23, 2003

Confirmation No.:

For: OPTIMIZED CORRECTION OF WAFER THERMAL DEFORMATION
IN A LITHOGRAPHIC PROCESS

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Sir:

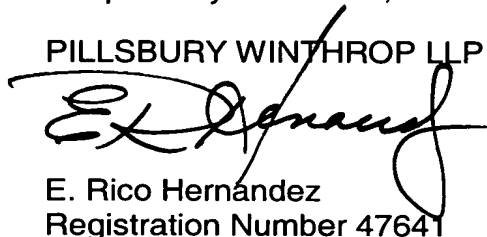
Pursuant to 37 CFR 1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

The undersigned respectfully notes that copies of U.S. references are not required in applications filed after June 30, 2003.

This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of the first Office Action on the merits in the present application. No certification or fee is required.

Respectfully Submitted,

PILLSBURY WINTHROP LLP



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Atty. Dkt. No.	M#	Client Ref.
	306369	P-0128.030-US

**INFORMATION DISCLOSURE STATEMENT
BY APPLICANT**

Applicant: OTTENS et al.
Appln. No.: TO BE ASSIGNED
Filing Date: December 23, 2003
Examiner: not assigned Group Art Unit: not assigned

Date: December 23, 2003 Page 1 of 1

U.S. PATENT DOCUMENTS

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR	6,447,964	09/2002	OKINO et al..			
	BR						
	CR						
	DR						
	ER						
	FR						
	GR						
	HR						
	IR						
	JR						
	KR						
	LR						
	MR						
	NR						

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name		English Abstract		Translation Readily Available	
							Enclosed	No	Enclose	No
	OR									
	PR									
	QR									
	RR									
	SR									
	TR									
	UR									
	VR									
	WR									
	XR									

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

	YR				
	ZR				
	AAR				
	BBR				
	CCR				
	DDR				

Examiner Date Considered:

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.